

## Supplementary Information

### Three-dimensional patterning of MoS<sub>2</sub> with ultrafast laser

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#### Plasma model combined with two temperature model

Because the bandgap of bulk MoS<sub>2</sub>, 1.8 eV, is higher than the photon energy, 1.5 eV, double-photon ionization is considered as the main method to generate free electrons. The following plasma equation is applied to calculate the free electron generation:<sup>[1,2]</sup>

$$\frac{\partial n_f}{\partial t} = P(I) - \frac{n_f}{\tau_{re}} \quad (1)$$

where  $n_f$  is the free electron density,  $t$  is the time,  $\tau_{re}$  is the free electron recombination time,  $P(I)$  is the photoionization term, and  $I$  is the laser intensity. The free electron recombination time  $\tau_{re}$  is considered a constant value at 180 ps, as measured for MoS<sub>2</sub> in a previous work.<sup>[3]</sup> The photoionization term can be calculated by formula for double-photon absorption as follows:<sup>[4]</sup>

$$P = \frac{\beta I^2}{2\hbar\omega} \quad (2)$$

$$I = \frac{2F}{\sqrt{\pi/\ln 2} t_p} (1 - R) \times \exp\left(-\frac{r^2}{r_0^2} - (4\ln 2) \left(\frac{t}{t_p}\right)^2\right) - \int_0^z \alpha_h(t, r, z) dz \quad (3)$$

where  $\hbar$  is the reduced Planck constant, and  $\omega$  is the laser frequency,  $F$  is the laser fluence,  $t_p$  is the pulse duration,  $r_0$  is the radius of the laser beam,  $\alpha_h$  is the free electron absorption coefficient.

Meanwhile, the ionized free electrons are also heated by an intense electromagnetic field during laser irradiation. The electron temperature during laser irradiation can be calculated using the following expression:<sup>[2]</sup>

$$c_e n_f \frac{\partial T_e}{\partial t} = \alpha_h I \quad (4)$$

where  $c_e$  is the specific heat of free electrons,  $T_e$  is the free electron temperature, which can be deduced from the free electron dielectric function. The specific heat of the free electrons can be deduced from the Fermi distribution.<sup>[5]</sup>

Based on eqs. 1–4, we can obtain the values of free electron density and temperature after laser pulse excitation. In this case, the energy of the laser pulse is transferred to the high energy free electron system. Subsequently, the high energy free electrons transfer energy to lattice and valence electrons through high energy electron induced lattice heating and valence electron ionization.

To describe lattice heating, the famous two-temperature model (TTM) was used to calculate the energy transfer between high energy electrons and lattice as follows: <sup>[5,6]</sup>

$$c_e \frac{\partial T_e}{\partial t} = \nabla[\kappa_e \nabla T_e] - G(T_e - T_l) + S \quad (5)$$

$$c_l \frac{\partial T_l}{\partial t} = G(T_e - T_l) \quad (6)$$

where  $\kappa_e$  is the free electron heat conductivity,  $G$  is the electron-lattice coupling factor,  $T_l$  is the temperature of the lattice,  $S$  is the laser source term, and  $c_l$  is the specific heat of the lattice. Because the processes of lattice heating and laser excitation were separated in time domains, the laser source term,  $S$ , was ignored in the simulation presented in eq. 5. The free electron heat conductivity can be

obtained as 4.2 cm<sup>2</sup>/s from experimental measurements.<sup>[5]</sup> The electron-lattice coupling factor can be estimated using the following:<sup>[5,7]</sup>

$$G = \frac{\pi^2 m_e n_f c_s^2}{6 \tau_{el} T_e} \quad (7)$$

where  $m_e$  is the mass of the electron,  $c_s$  is the sound speed in MoS<sub>2</sub>, and  $\tau_{el}$  is the free electron relaxation time. The sound speed can be obtained using  $c_s = \sqrt{B/\rho}$ , where  $B$  is the bulk modulus ( $B=2.4 \times 10^{12}$  Nm<sup>-2</sup>), and  $\rho$  is the mass density of MoS<sub>2</sub> ( $\rho=4.8$  gcm<sup>-3</sup>). The specific heat of the lattice can be deduced from the Debye model.<sup>[4]</sup>

In a previous work on the laser induced superheat of a semiconductor, the plasma frequency  $\omega_p$  was reported to increase with lattice temperature as follows:<sup>[8]</sup>

$$\omega_p^{-1} \frac{\partial \omega_p}{\partial T_l} = K_c \quad (8)$$

where  $K_c=8.2 \times 10^{-4}$ , and the plasma frequency  $\omega_p$  is a function of the free electron density  $n_f$ :<sup>[1,8]</sup>

$$\omega_p^2 = \frac{n_f e^2}{m_e \epsilon_0} \quad (9)$$

where  $\epsilon_0$  is the vacuum dielectric constant ( $\epsilon_0=3.915+3.166i$ ). Based on eqs. 8–9, we can obtain the relationship between free electron density and lattice temperature. Therefore, the electron density evolution can be calculated after laser pulse excitation.

The transient optical property can be described as the dielectric function of laser induced plasma. There are mainly two contributions to the dielectric function for semiconductors (*e.g.*, free electrons and valence electrons). In some previous works,<sup>[9,10]</sup> the dielectric function change was only determined

by the effect of free electrons, where the contribution of free electrons to the dielectric function is widely described by the Drude-Lorentz model.<sup>[1]</sup> For transparent material, the contribution of valence electrons is so small that it can be ignored. However, the effect of valence electrons on the dielectric function should be taken into account, especially when valence electron density considerably decreases because of strong ionization. Therefore, to determine the contribution of valence electrons, the dielectric function should be expressed as follows:<sup>[11]</sup>

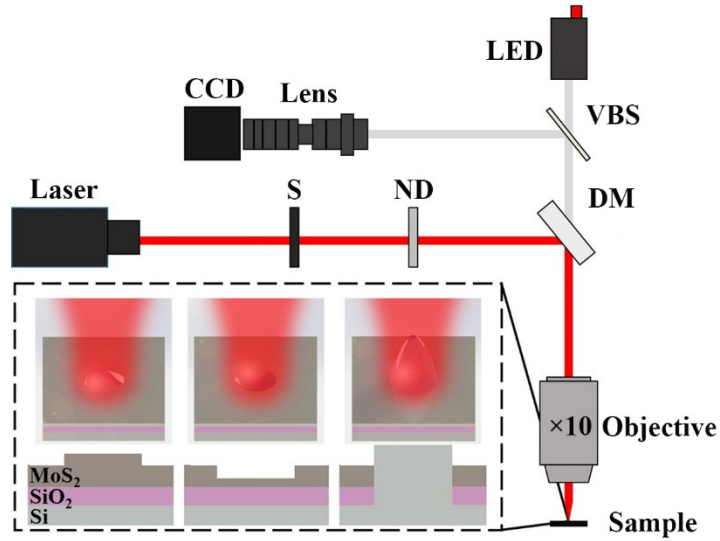
$$\varepsilon = \left( 1 + \frac{3(n_0 - n_f)\chi}{3 - (n_0 - n_f)\chi} \right) - \frac{\omega_p^2}{\omega^2 + i\omega\Gamma} \quad (10)$$

where  $\varepsilon$  is the dielectric function,  $n_0$  is the original valence electron density in bulk MoS<sub>2</sub>,  $\omega$  is the laser frequency,  $\chi$  is the electric susceptibility derived from the Clausius–Mossotti relation ( $\chi=0.9672+0.1114i$ ), and  $\Gamma$  is the free electron scattering rate.<sup>[1]</sup> The free electron scattering rate is attributed to the effect of electron-lattice scattering and electron-electron scattering.<sup>[4]</sup> When the dielectric function is determined, the time-resolved reflection can be calculated in the laser irradiated area as follows:<sup>[12]</sup>

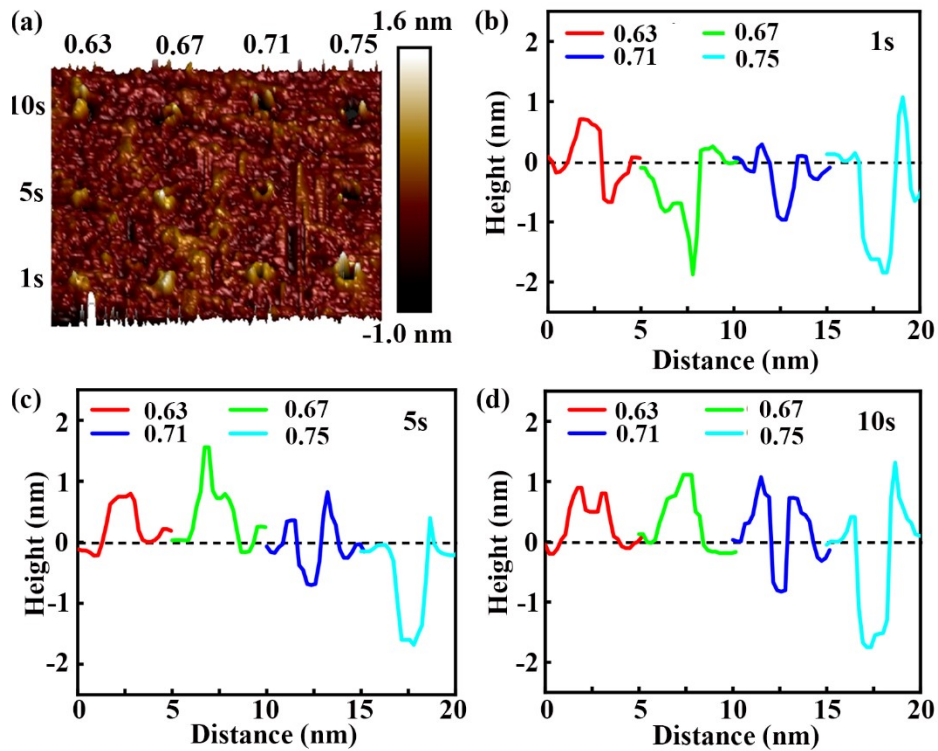
$$R = \frac{(n - 1)^2 + \kappa^2}{(n + 1)^2 + \kappa^2} \quad (11)$$

where  $n$  and  $\kappa$  are the refraction index and the extinction coefficient, respectively, which can be deduced from the dielectric function by  $n + i\kappa = \sqrt{\varepsilon}$ .

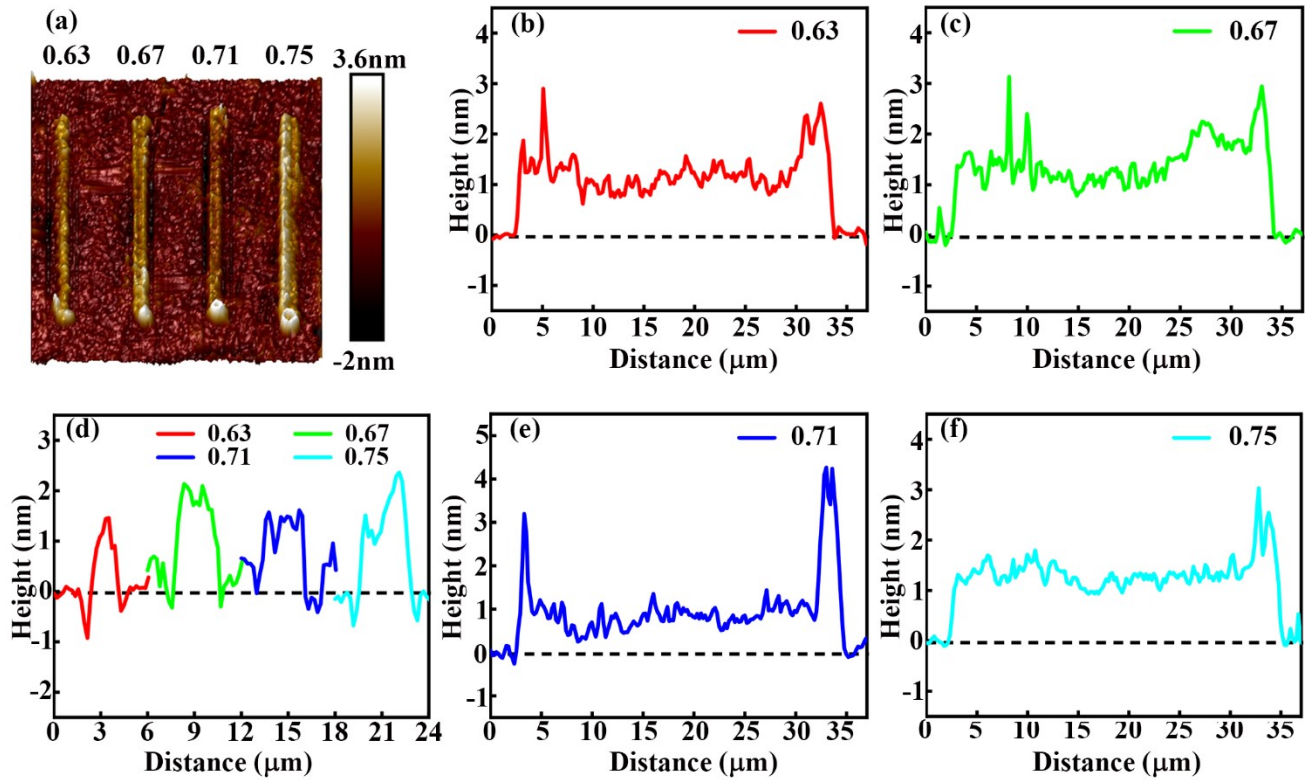
Based on the discussion aforementioned, we combined plasma and two temperature model to account for the electron dynamics of MoS<sub>2</sub> during intense femtosecond laser pulse irradiation. The simulation results were analyzed and compared with the experimental results.



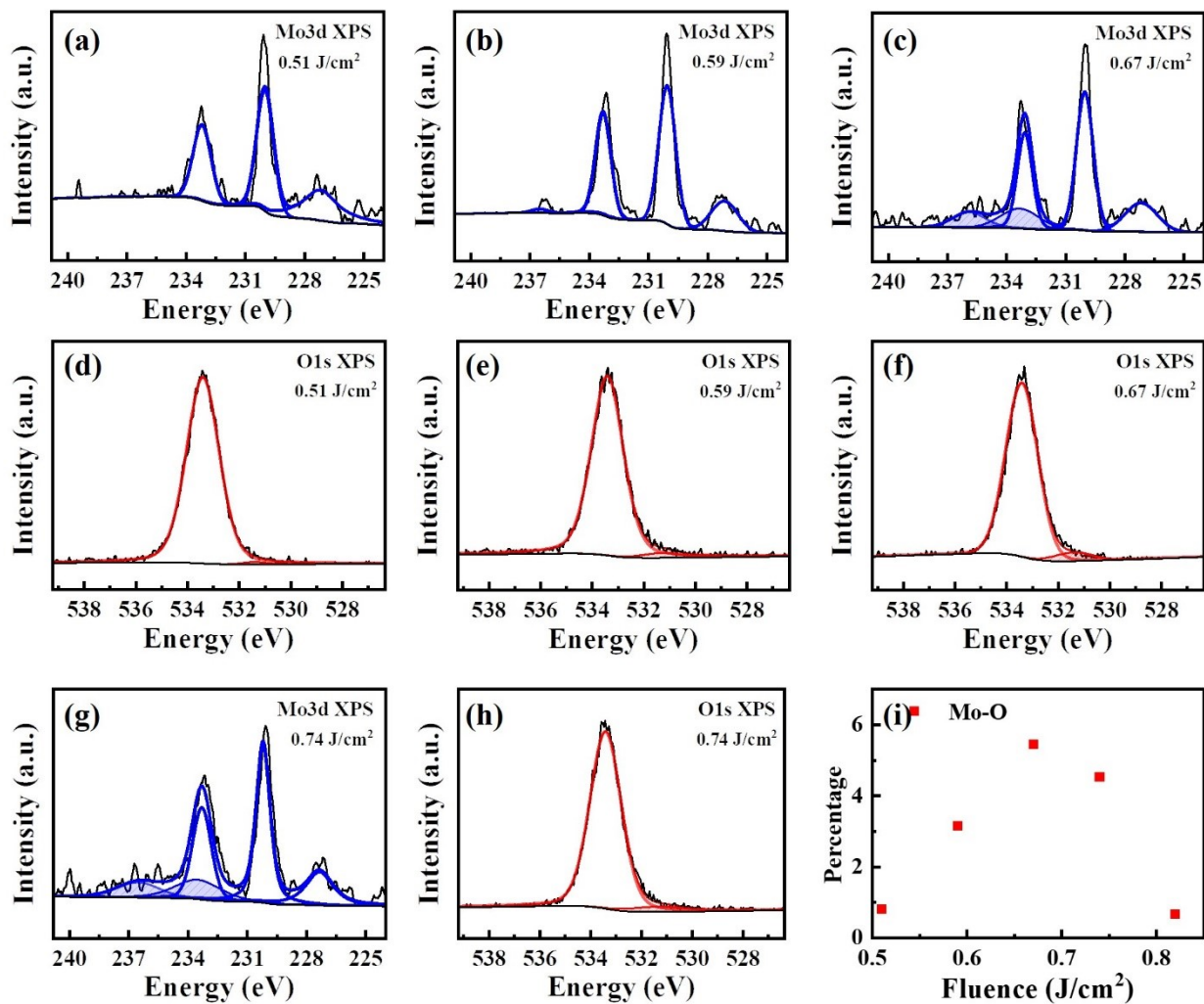
**Figure S1.** Schematic illustration of experimental setup for processing MoS<sub>2</sub> using a femtosecond laser.



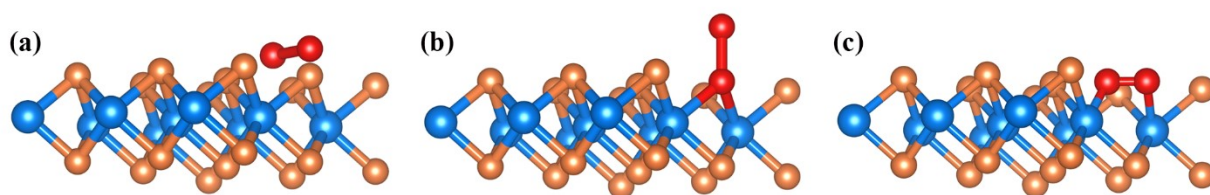
**Figure S2.** Surface morphologies of point processing. (a) AFM topography of points ablated using ultrafast laser with different fluence and time. AFM height images of points ablated using ultrafast laser with (b) 1s, (c) 5s and (d) 10s.



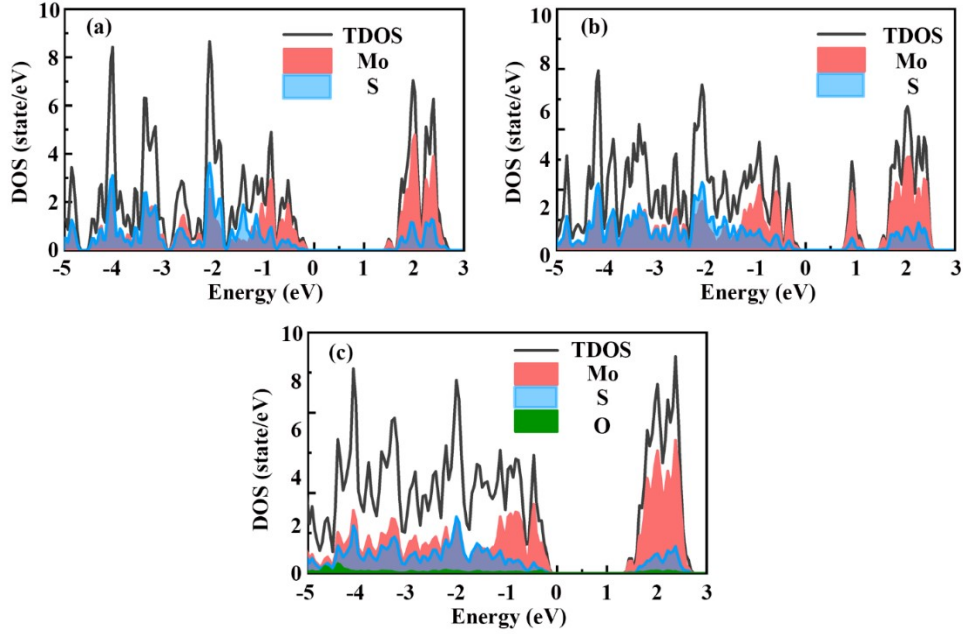
**Figure S3.** Surface morphologies of line processing. (a) AFM topography of line ablated using ultrafast laser with different fluence. AFM height images of lines ablated using ultrafast laser with (b) 0.63 J/cm<sup>2</sup>, (c) 0.67 J/cm<sup>2</sup>, (e) 0.71 J/cm<sup>2</sup> and (f) 0.75 J/cm<sup>2</sup>. (d) The AFM height comparison ablated using ultrafast laser with different fluence.



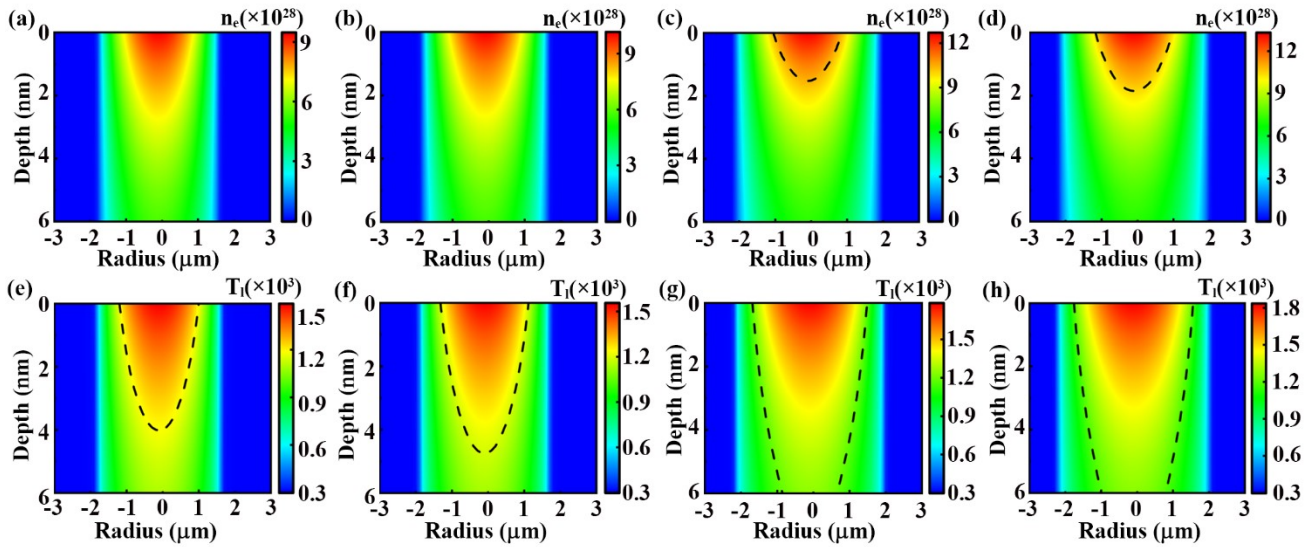
**Figure S4.** XPS spectrum of oxygen and molybdenum in MoS<sub>2</sub> after laser patterning with different fluence.



**Figure S5.** Crystal structures for (a) Configuration II, (b) Configuration III, (c) Configuration IV.

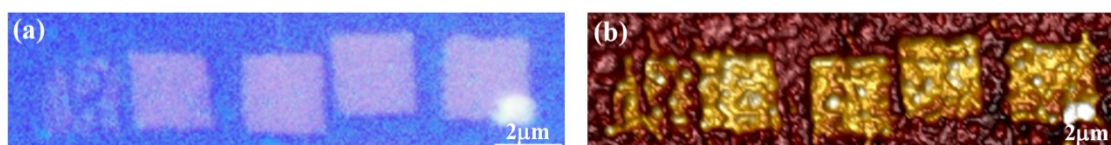


**Figure S6.** Electronic density of states obtained through DFT of (a) pristine MoS<sub>2</sub>, (b) MoS<sub>2</sub> with S vacancies, (c) MoS<sub>2</sub> with O substituting S. Zero at the energy scale corresponds to the Fermi level.

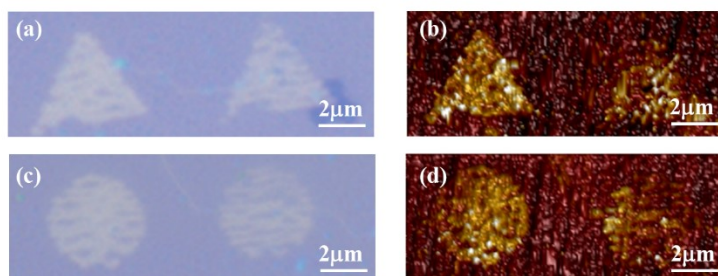


**Figure S7.** Calculated electron densities ablated by femtosecond laser pulse with different fluence of (a) 0.64, (b) 0.66, and (c) 0.74 J/cm<sup>2</sup> and (d) 0.76 J/cm<sup>2</sup>. Calculated temperature distributions ablated by femtosecond laser pulse with different fluence of (e) 0.64, (f) 0.66, and (g) 0.74 J/cm<sup>2</sup> and (h) 0.76 J/cm<sup>2</sup>.





**Figure S8.** The optical image and AFM topography of square patterns using ultrafast laser with different fluence from 0.58~0.68 J/cm<sup>2</sup>.



**Figure S9.** The optical image and AFM topography of (a, b) triangle and (c, d) circle patterns using ultrafast laser with different fluence from 0.58~0.68 J/cm<sup>2</sup>.

## References

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